

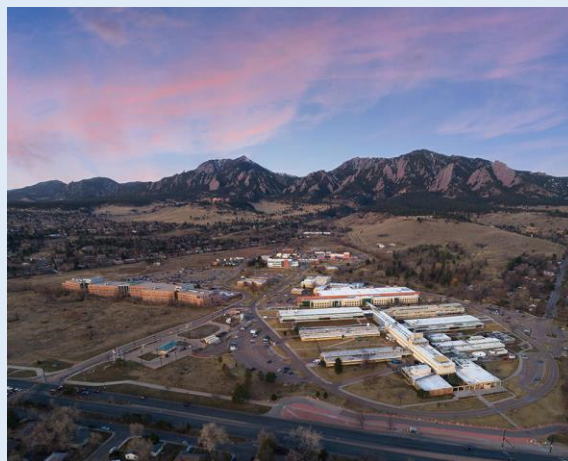
# 2019 High Frequency Scanning Probe Microscopy Workshop



**Thursday and Friday, December 12 & 13, 2019**  
**National Institute of Standards and Technology (NIST)**  
**Boulder, Colorado**

Local, near-field probing is a powerful technique for studying electromagnetic material properties with sub-wavelength resolution. In turn, near-field scanning probe microscopy impacts fundamental research and applications in a wide variety of fields, including quantum materials, low-dimensional systems, superconductivity, biological systems, and nanoscale fabrication. To date, the most prominent near-field probing results have been in the visible and near- to mid-infrared regimes. Near-field probing at longer wavelengths – including the microwave, mm-wave/THz, and far-infrared regimes – is less mature, but presents broad, emerging research opportunities in quantitative electromagnetic material and device characterization. This workshop will bring together researchers in microwave, THz, and far-infrared scanning probe microscopy to share breakthroughs in research, exchange ideas about this emerging field, and encourage new collaborations.

Join researchers from academia, industry, and government laboratories for this two-day workshop on all aspects of near-field, high frequency scanning probe microscopy from microwaves through THz and to the far-infrared.



Website:

<https://www.nist.gov/news-events/events/2019/12/high-frequency-scanning-probe-microscopy-workshop>

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